

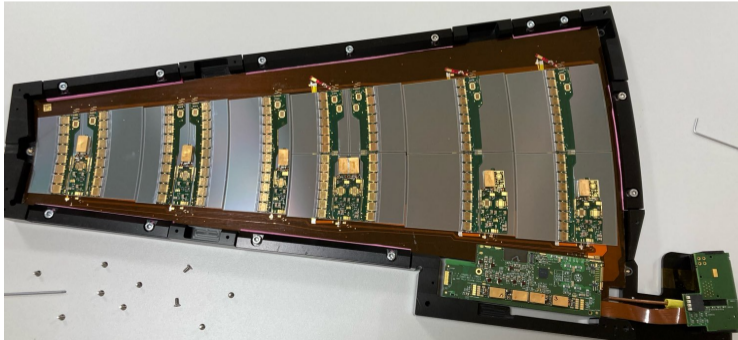
Overview of the Passive CMOS Strip detectors

Marta Baselga, Spyridon Argyropoulos, Jan-Hendrik Arling, Naomi Davis, Leena Diehl, Ingrid-Maria Gregor, Fabian Hügging, Hannah Jansen, Michael Karagounis, Kevin Kröninger, Fabian Lex, Ulrich Parzefall, Arturo Rodriguez, Surabhi Sharma, Simon Spannagel, Dennis Sperlich, Niels Sorgenfrei, Jens Weingarten, Iveta Zatocilova

2/12/2022 - 41st RD50 Workshop, Sevilla

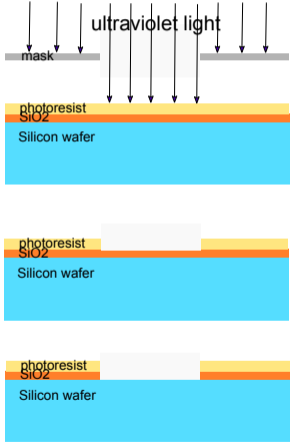
Motivation

- All ATLAS and CMS upgrade strip detectors are fabricated in Hamamatsu Photonics HPK
- Seems like large area strips only are fabricated in microelectronics foundries
- Here we want to show that also CMOS foundries can fabricate strip detectors and do not have any impact in the performance

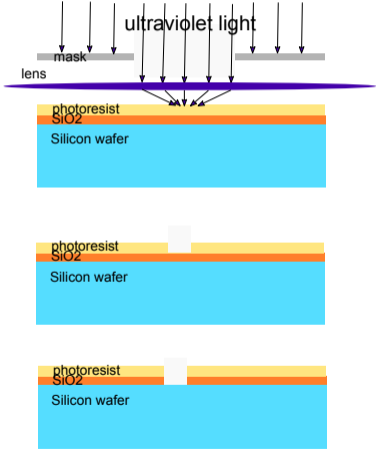


What changes regarding microelectronic foundries?

Microelectronics photolithography



CMOS photolithography



Semiconductor device fabrication



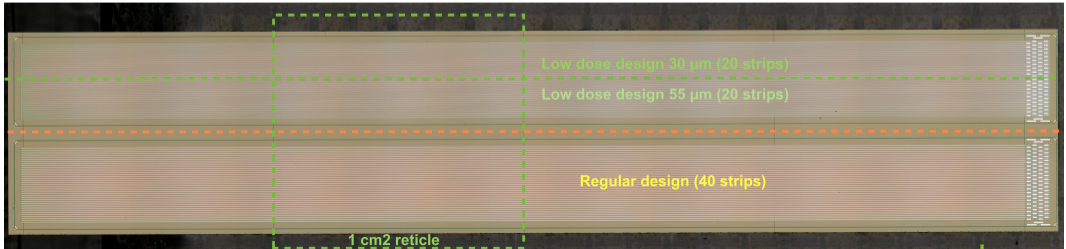
MOSFET scaling (process nodes)

10 μm	– 1971
6 μm	– 1974
3 μm	– 1977
1.5 μm	– 1981
1 μm	– 1984
800 nm	– 1987
600 nm	– 1990
350 nm	– 1993
250 nm	– 1996
180 nm	– 1999
130 nm	– 2001
90 nm	– 2003
65 nm	– 2005
45 nm	– 2007
32 nm	– 2009
22 nm	– 2012
14 nm	– 2014
10 nm	– 2016
7 nm	– 2018
5 nm	– 2020
Future	
3 nm	– 2022
2 nm	– 2023

[Image from wikipedia]

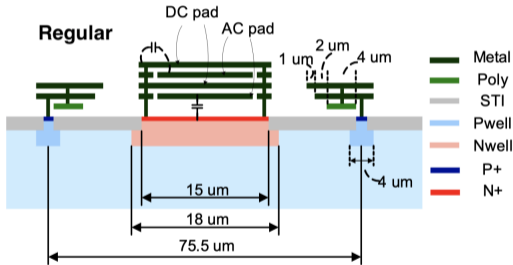
Passive CMOS Strip

- Fabrication in LFoundry with a 150 nm production
- NO electronics included → therefore Passive
- FZ 150 μm thick wafer
- We fabricated 2.1 cm and 4.1 cm long strips:
 1. 1 cm^2 reticle used (2 set of masks used)
 2. The strips had to be stitched 3 or 5 times
- We want to demonstrate that stitching does not affect the performance of the strips



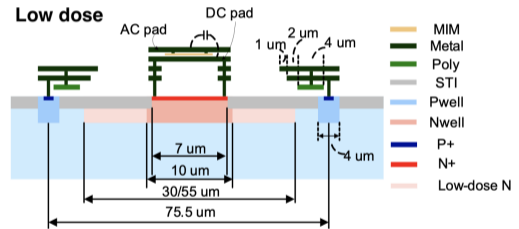
Two designs of strips: Regular design and Low Dose design

Regular design



- Similar to the ATLAS strip design

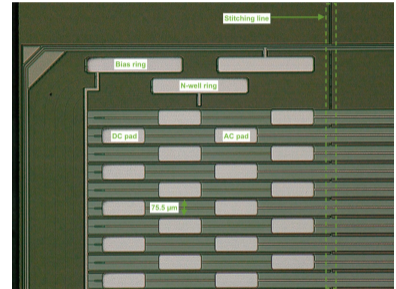
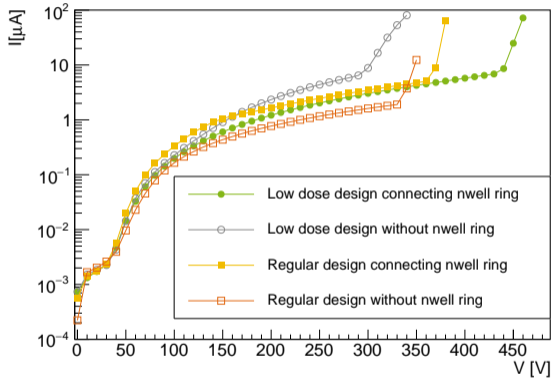
Low dose design



- Using low dose implant and a MIM capacitor

Electrical characterization: IV

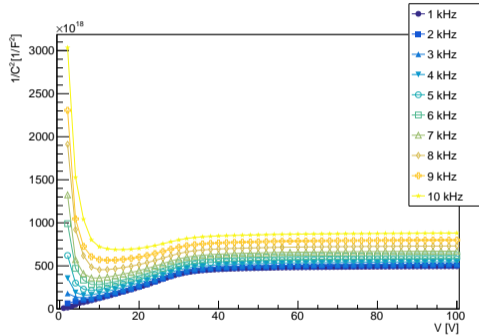
IV comparison with and without nwell connected



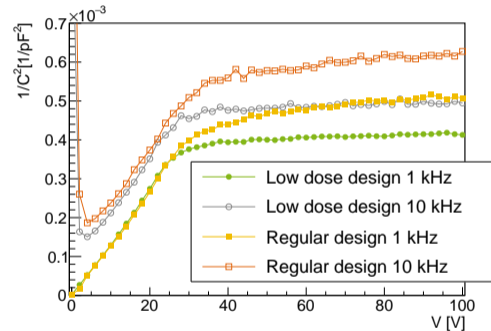
- IV curve shows an improvement when biasing the bias and the nwell ring together
- Probably the break down is happening to the edge of the detector

Electrical characterization: CV

CV with the bias pad



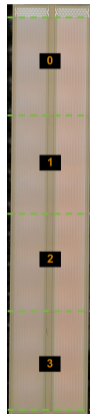
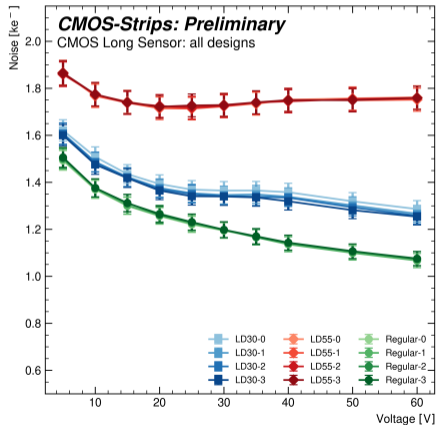
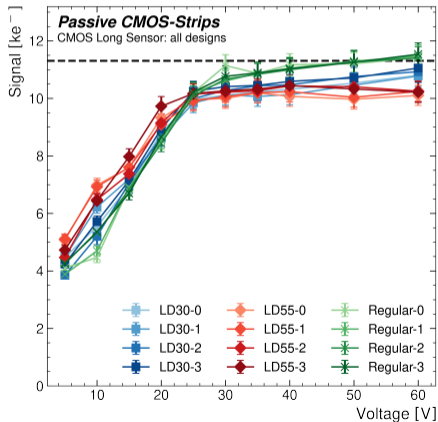
CV with the bias pad and nwell ring



- Decrease of capacitance when increasing the frequency (small discrepancy with the results presented by S. Mägdefessel)
- The effect decreases biasing the nwell ring → some edge effect

Charge in the ALiBaVa setup

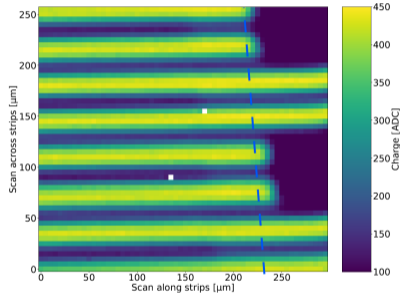
Signal of a long detector with Sr^{90} source



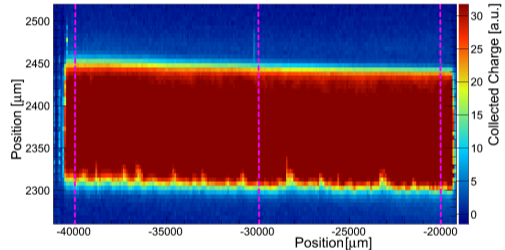
[NIMA 1033 (2022) 166671]

Transient Current Technique measurements

TCT and edge TCT with IR laser



Collected charge of the regular design of a long sensor as a function of the laser position at 50 V, illuminating from top. [NIMA 1033 (2022) 166671]

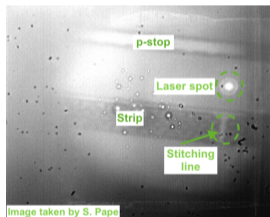


Edge TCT charge from a short LD30 sensor at 100 V (fully depleted). Stitching does not change the collected charge. [N. Sorgenfrei, 40th RD50, CERN]

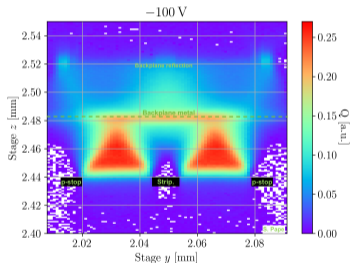
Two Photon Absorption Transient Current Technique measurements

- TPA-TCT measurements were performed at CERN SSD
- The charge in stitching and outside stitching does not show any difference

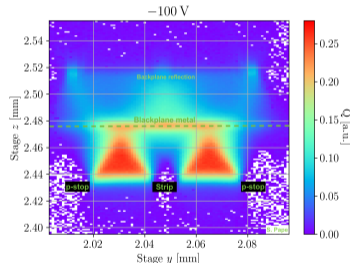
IR image



TPA-TCT in the stitch area



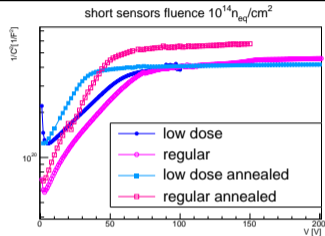
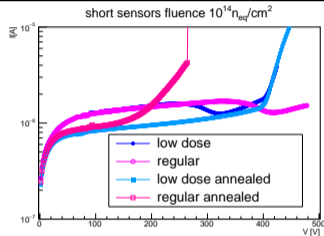
TPA-TCT outside the stitch



- Thanks to Sebastian Pape, Michael Moll, Marcos Fernandez Garcia, and Esteban Curras for the TPA-TCT measurements (ask them the questions about TPA-TCT)
- Check Sebastian's [talk](#) about the setup and measurements

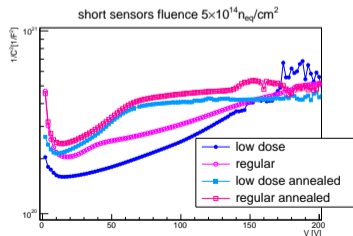
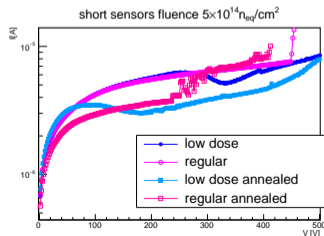
Irradiated with protons at KIT

- 23 MeV protons at fluence $1 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2$



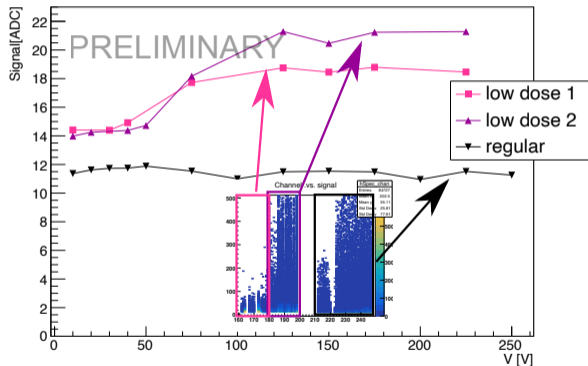
CV at 1 kHz

- 23 MeV protons at fluence $5 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2$



CV at 1 kHz

Irradiated with protons at KIT (23 MeV and annealed)

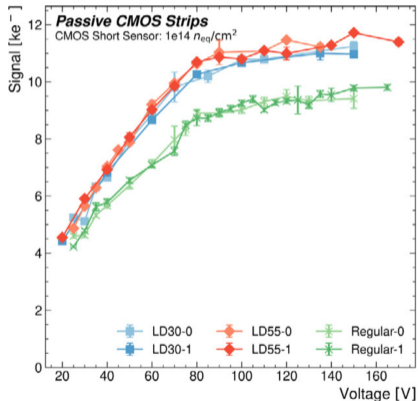


- Data not calibrated
- Regular design seems to stop working after irradiation

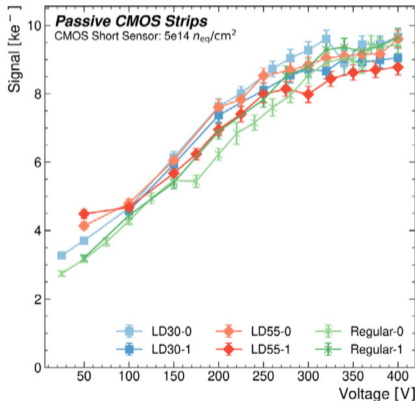
[12th PSD 2021 Birmingham]

Irradiated: Charge in the ALiBaVa setup with Sr⁹⁰

Signal of a short detector with Sr⁹⁰ source irradiated



Neutrons fluence $1 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2$



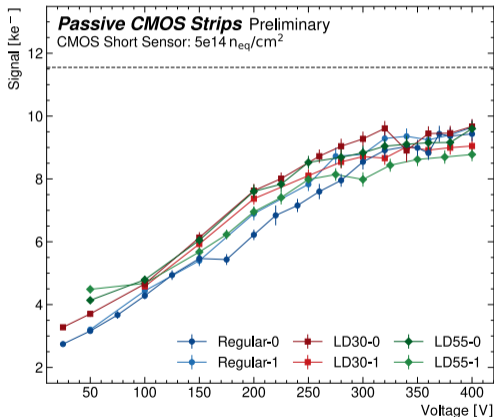
Neutrons fluence $5 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2$



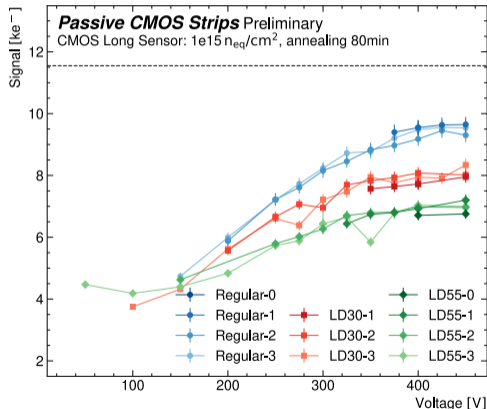
[NIMA 1039 (2022) 167031]

Irradiated: Charge in the ALiBaVa setup with Sr⁹⁰

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Neutrons $5 \times 10^{14} \text{ n}_{\text{eq}}/\text{cm}^2$

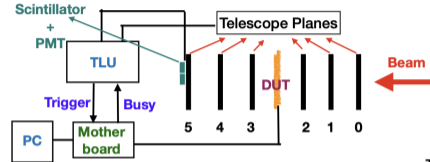
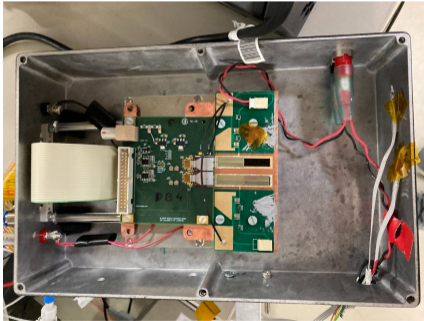


Neutrons $1 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$

[N. Sorgenfrei, 40th RD50, CERN]

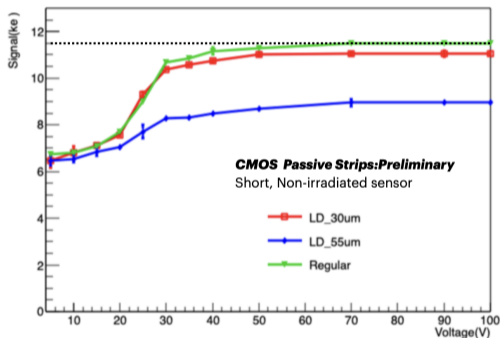
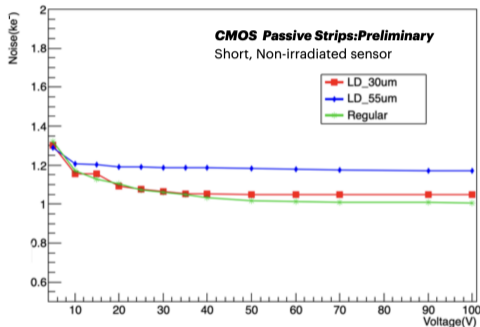
Testbeam campaigns

- Several Testbeams were done at DESY
- Electrons between 3 GeV and 3.4 GeV were used
- DAQ with ALiBaVa



Unirradiated sensor data @ 100 V bias voltage

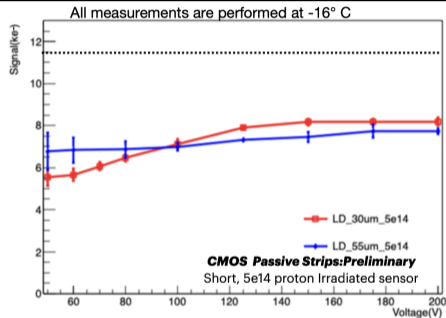
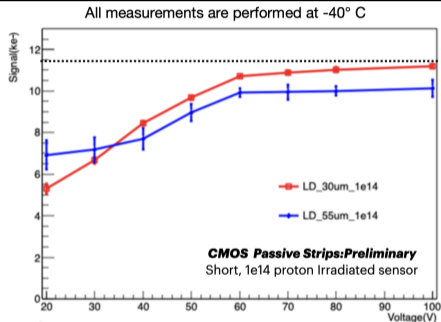
All measurements are performed at 18° C



- The charge is similar as the lab tests
- Low Dose 55 μm design shows lower charge related to the Beetle chip configuration

[10th BTTB 2022, Lecce, Italy]

Sensors irradiated with 23 MeV protons @KIT



- Regular design does not show charge, still to be investigated
- The sensors are still working after irradiation with protons
- Implementation of ALiBaVa data to Corryvreckan ongoing

Conclusions

- So far, stitching does not have any impact in the performance of the strip detectors before and after irradiation
- Currently the implementation of ALiBaVa in Corryvreckan is ongoing (great work from Fabian Lex)
- Finishing some pending measurements (such as Corryvreckan reconstruction or irradiation with high energy protons measurements)

Future work

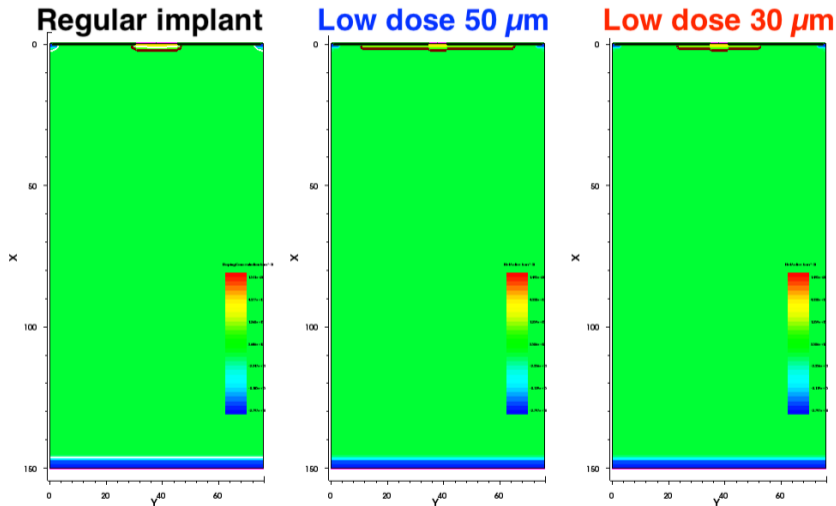
- Planning a new production with the electronics implemented in the strips is ongoing → that would allow to avoid all the bondings of the strips to the chips
- Production of a full wafer size strip detector with a CMOS foundry

Acknowledgements

The measurements leading to the test beam results have been performed at the Test Beam Facility at DESY Hamburg (Germany), a member of the Helmholtz Association (HGF)

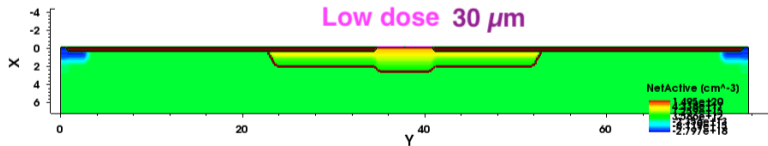
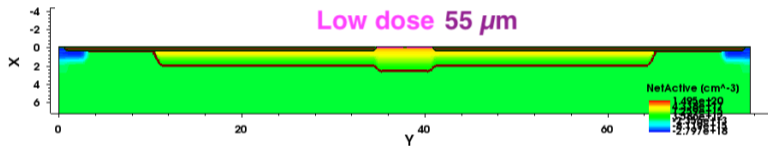
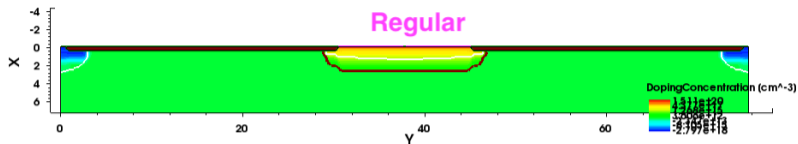
Backup

TCAD simulations: Simulated device



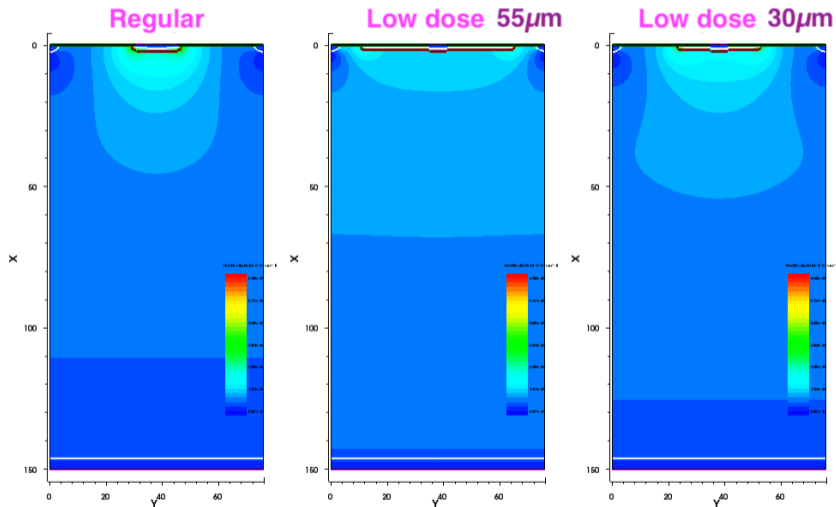
38th RD50 Workshop (On Line), June 2021

TCAD simulations: Simulated device zoom



38th RD50 Workshop (On Line), June 2021

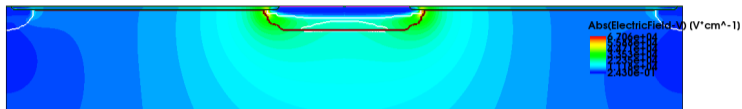
TCAD simulations: Simulated Electric field at 100 V



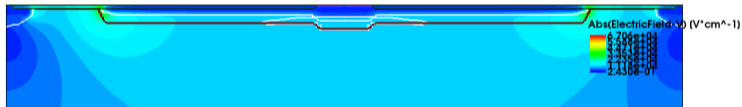
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TCAD simulations: Electric field zoom

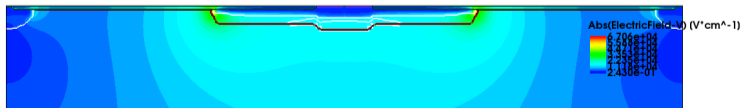
Regular implant



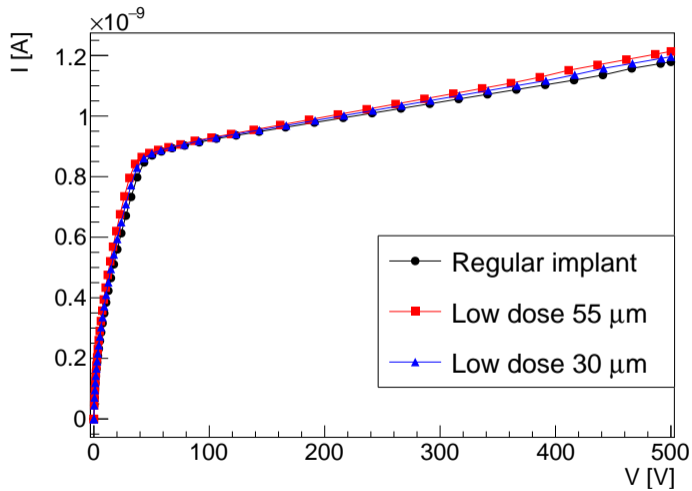
Low dose 55 μm



Low dose 30 μm

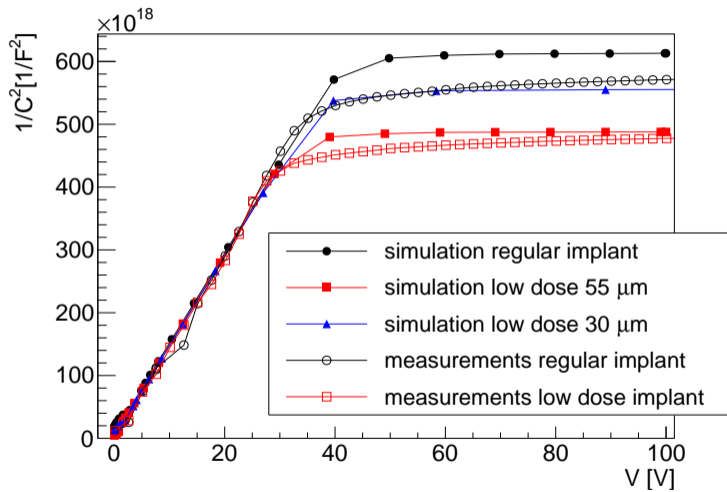


TCAD simulation: Current voltage curve



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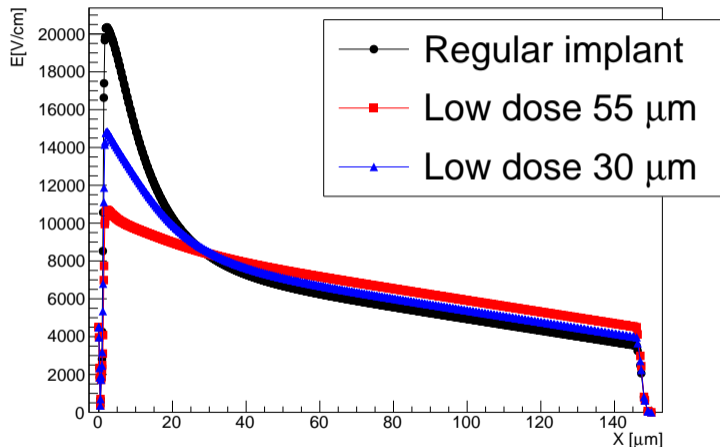
TCAD simulation compared with data: capacitance voltage curves



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TCAD simulation: Electric field 100 V at the center of the strip

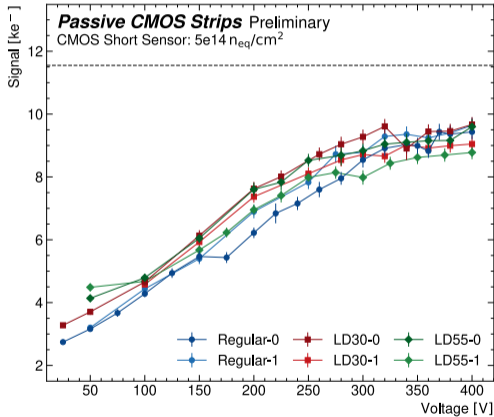
Electric field in the center of the strip



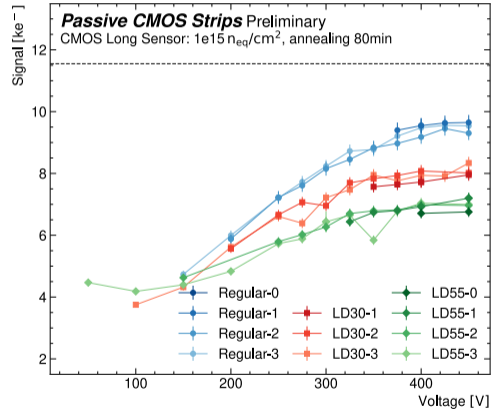
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Neutrons $1 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$

[N. Sorgenfrei, 40th RD50, CERN]

